

GLAST Silicon Strip Detectors (SSD)

Protoyping Procurement Testing



Delivery of Prototypes

	How many	By When	Tested by	Where?
HPK	10	mid-Dec '00	Mid-Jan	SLAC/Pisa?
	25	mid-Dec '00	Mid-Jan	Hiroshima
Micron	50	mid-Jan '01?	Mid Feb '01?	Trieste
ST	?	?		Pisa?
CSEM	?	March '01	March '01	Perugia

Objectives:

Qualify vendors, including wire bonding Establish testing procedures Test parameter cut-offs (specs)



Testing to "Qualify HPK Masks" Dec '00/Jan '01

- Type Vendor Number of detectors Number of cu-offs Expected shipping date
- : GLAST prototype detectors
- : Hamamatsu Photonics HPK
- : 35
- : 35
- : End of December 2000 to Hiroshima, (25 real and 25 cut-offs)
- : Beginning of January 2001 to SLAC, (10 real and 10 cut-offs)

Important Deadline : Jan 31, 2001

- Give Go-ahead to HPK for pre-production of 400 detectors . -



Testing to "Qualify HPK Masks" Dec 00/Jan 01

Prototype Testing at Hamamatsu

1) IV curve up to 200 with 5 V step.

2) Bad channel are measured by a RC-constant measurement and listed.

They will be classified as:

- a) coupling capacitor short circuit
- b) Al electrode short circuit with neighbors
- c) Al electrode continuity check to the end
- d) Isolation between adjacent implant-strips
- e) Connection of bias resistor and implant-strip
- 3) In each lot, following items are checked in sampling:
 - a) resistance of implant strip
 - b) resistance of Poly-Si resistor
 - c) Isolation resistance measurement between adjacent strips
- 4) Process verification by vendor



Testing to "Qualify HPK Masks" Dec 00/Jan 01

Prototype Testing at Hiroshima

Dec.25, 2000 - Jan.20, 2001 Test 5 detectors

I-V curve confirmation
 C-V curve confirmation
 strip by strip leakage current at 100V and at 200V
 sample measurement of bias resistance

Baby detector or test-structure measurements:1) diode CV curve2) isolation between adjacent strips

Jan.20 2001- Mar. 2001 Gamma-ray Irradiation

Check the same characteristics after irradiation.



Testing to "Qualify HPK Masks" Dec '00/Jan '01

Prototype Testing at SLAC/Pisa (T. Handa) Jan.8-20, 2001 Test 5 detectors + 5 cut-offs

Visual inspection Measure dimensions of mask, saw cut, thickness

I-V curve confirmation		
C_body - V	(Full depletion voltage) [1 kHz]	1 day
C_interstrip-V	(3 strips in a detector) [1 MHz]	1 day
C_coupling-V	(3 strips in a detector) [1 MHz]	1 day
Bias resistor resista	nce (3 strips in a detector)	1 day

Bonding of test detectors, i-V before and after

Jan.22-31, 2001 Gamma-ray Irradiation for 3 baby detectors, 10 krad Co60 Check the same characteristics above after irradiation.

Jan 8 – March 31 2001:

Verify all spec'ed parameters and establish testing procedures Establish performance of baby detectors vis-à-vis sensors.



Testing to "Qualify other Masks" Early 2001

Jan./Feb 01 ST and Micron detectors Trieste? Pisa? Liverpool? SLAC?

Visual inspection
Measure dimensions of mask, saw cut, thickness, Mask alignment
I-V curve confirmation
C_body - V (Full depletion voltage) [1 kHz]
C_interstrip-V (3 strips in a detector) [1 MHz]
C_coupling-V (3 strips in a detector) [1 MHz]
Bias resistor resistance (3 strips in a detector)

Bonding of test detectors, i-V before and after

Gamma-ray Irradiation for 3 detectors, 10 krad Co60 Check the same characteristics above after irradiation.

Verify all spec'ed parameters Establish performance of baby detectors vis-à-vis sensors

HPK Procurement Schedule

Assumption: Test Prototypes in January '01 Give go ahead for Pre-production runs at the end of January '01

2001 Preproduction | Mass production Feb March April May June July Aug Sep Oct Start 145 130 120 200 500 500 500 \rightarrow @ 500/month will finish June '03 Have to accelerate production: HPK plans to finish production Dec '02, with a late date of March '03.

Mech. Samples ~ 30 20 20 40 80 80 80 $|340 \approx 11 \text{ trays}$ Note:

Need to plan for shipping, storage. My preference: store at HPK until demanded by assembly





GLAST Testing during the Silicon Procurement

Acceptance QC: sensors High quality SSD \rightarrow testing of detectors including single channels is done by vendor. Measurement of the sensor leakage currents (i-V) is done by GLAST assembly institution

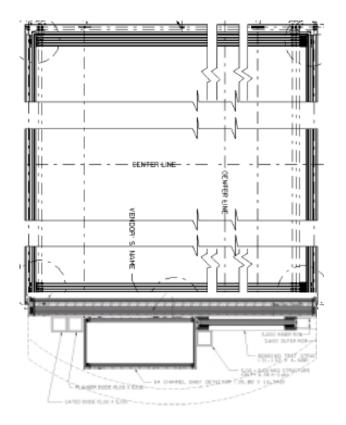
Process Control: test structures

Thorough test of specs on test structures, one out of every lot (48) by Hiroshima & SLAC? Test wire bonding on test structures

Assembly: sensors

Testing after bonding and encapsulation (I-V and caps) by GLAST assembly institution will go on during detector procurement and has to keep pace with the delivery of SSD's

GLAST Testing during the Silicon Procurement



Acceptance QC: sensors

Process Control: test structures



GLAST Testing during the Silicon Procurement

Data base:

HPK – Assembly Institution – Testing Institution – GLAST IPO

E-mail from T. Ohsugi

Let's think about data base of sensors delivered from Hamamatsu. For ATLAS sensor data, Hamamatsu is going to develop the data base in web page in which all of detail taken in Hamamatsu are listed. Former my student who started working with Mr. Yamamura since July is now developing the ATLAS system. He is quite experienced in sensors and computer.

I think we would be better to follow the ATLAS scheme and develop a similar system at Hamamatsu. Then we can look at and/or we can down load the data anytime. We should make a miller site of the data base in Hiroshima and add some measured at Hiroshima. Slac should have own data base, shoud`nt you?



Testing:

Tasks Rate

Qualifying:

1)	Qualify Prototype Mask & Process	Specs	10/2 weeks
2)	Establish Test Procedures (freq., delay, etc)	Specs	35/8 weeks
3)	Establish Correspondence Sensor- Baby detectors	Specs	35/8 weeks

Production: 5 Steps

-assumes ladder production in step with sensor production-

2)	Testing of flight sensors at factory	Bad Channels,	
		i-V	500/month
3)	QA on 1 test structure/lot during production	Specs	10/month
4)	Quick test right before ladder assembly	i-V	500/month
5)	Testing ladder after wire bonding	caps, i-V	~6/day
6)	Testing before tray assembly (3 month)	i-V	~50/day